

Symposium (Oral) | Symposium | Highly reliable metallization technology for long term retention

## [15p-304-1~10]Highly reliable metallization technology for long term retention

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△ : Presentation by Applicant for JSAP Young Scientists Presentation Award

▲ : English Presentation

▼ : Both of Above

No Mark : None of Above

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2:45 PM - 3:15 PM

## [15p-304-4]Ellipsometry for evaluating surface cleanliness

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Keywords: defect inspection, ellipsometry

Detection of defects and contaminations is of crucial importance for realizing high-reliable interconnects. To determine physical nature of defects is also becoming important. In the BEOL technologies, various processes such as CMP are involved and versatile inspection ways are demanded in from basic R&D to manufacturing. Ellipsometry is a technique to detect substances on a surface selectively. In this paper application of ellipsometry to BEOL materials are presented.